


**TRANSMITTAL**

Electronic Version v1.1

Stylesheet Version v1.1.0

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| <b>Title of Invention</b>   | HIGH-PRESSURE PROCESSING CHAMBER FOR A SEMICONDUCTOR WAFER |   |
| Application Number :  | 10/680783  |  |
| Date :  | 2003-10-06   |   |
| First Named Applicant:  | Jones William Dale   |   |
| Confirmation Number:  | 5859   |   |
| Attorney Docket Number:   |  |   |
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| Documents being submitted: | Files   |
|----------------------------|---|
| us-ids                     | SSI04001-usidst.xml<br>us-ids.dtd<br>us-ids.xsl |
| Comments                   |   |